

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L6	10929	mems micromechanical\$4 microelectromechanical\$4 "micro-mechanical" "micro-electro-mechanical"	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/01 13:19
L7	499	L6 and ((silicon polysilicon "poly-si" polycrystalline si) with (remov\$6 etch\$6 sacrificial disposable))	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/01 13:19
L8	163	L7 and (releas\$6 mov\$6 mirror micromirror reflect\$6)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/01 13:19
L9	122	((mems micromechanical\$4 microelectromechanical\$4 "micro-mechanical" "micro-electro-mechanical") and (silicon polysilicon "poly-si" polycrystalline si) and (remov\$6 etch\$6) and (sacrificial disposable) and (releas\$6 mov\$6 mirror micromirror reflect\$6)).clm.	US-PGPUB	OR	ON	2006/03/01 14:47
L10	105	((mems micromechanical\$4 microelectromechanical\$4 "micro-mechanical" "micro-electro-mechanical") and (silicon polysilicon "poly-si" polycrystalline si) and (remov\$6 etch\$6) and (sacrificial disposable) and (releas\$6 mov\$6 mirror micromirror reflect\$6) and (dielectric insulat\$6 oxide dioxide nitride)).clm.	US-PGPUB	OR	ON	2006/03/01 14:50
L11	65	((mems micromechanical\$4 microelectromechanical\$4 "micro-mechanical" "micro-electro-mechanical") and (silicon polysilicon "poly-si" polycrystalline si) and (remov\$6 etch\$6) and (sacrificial disposable) and (releas\$6 mov\$6 mirror micromirror reflect\$6) and (soi "silicon-on-insulator" "silicon on insulator" sos "silicon-on-sapphire" "silicon on sapphire")).clm.	US-PGPUB	OR	ON	2006/03/01 14:52
L12	114	10 11	US-PGPUB	OR	ON	2006/03/01 14:52
S1	9	("5216490" "5343064" "5479042" "5725729" "5882532" "6021675" "6044705" "6121552" "6433401").PN.	US-PGPUB; USPAT	OR	OFF	2006/02/27 17:14

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S2	3	ep-834759-\$.did. de-19847455-\$. did.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2006/02/27 16:31
S3	1	2000-330066.NRAN.	DERWENT	OR	OFF	2006/02/27 16:41
S4	5236	438/48.ccls. 438/50.ccls. 438/52. ccls. 438/53.ccls. 438/72.ccls. 438/455.ccls. 438/459.ccls. 438/719.ccls. 438/739.ccls. 438/753.ccls.	US-PGPUB; USPAT	OR	OFF	2006/02/28 13:05
S5	505	438/50.ccls.	US-PGPUB; USPAT	OR	OFF	2006/02/28 12:55
S6	49513	mems micromechanical\$4 microelectromechanical\$4 "micro-mechanical" "micro-electro-mechanical"	US-PGPUB; USPAT	OR	ON	2006/02/28 13:09
S7	3215	S6 same ((silicon polysilicon "poly-si" polycrystalline si) with (remov\$6 etch\$6 sacrificial disposable))	US-PGPUB; USPAT	OR	ON	2006/03/01 14:45
S8	335	S6 same ((silicon polysilicon "poly-si" polycrystalline si) with (remov\$6 etch\$6) with (sacrificial disposable)) same (releas\$6 mov\$6 mirror micromirror reflect\$6)	US-PGPUB; USPAT	OR	ON	2006/02/28 13:49
S9	537	S6 same ((silicon polysilicon "poly-si" polycrystalline si) with (remov\$6 etch\$6) with (sacrificial disposable))	US-PGPUB; USPAT	OR	ON	2006/02/28 13:03
S10	5247	(438/48.ccls. 438/50.ccls. 438/52. ccls. 438/53.ccls. 438/72.ccls. 438/455.ccls. 438/459.ccls. 438/719.ccls. 438/739.ccls. 438/753.ccls.)	US-PGPUB; USPAT	OR	OFF	2006/02/28 13:06
S11	406	S7 and S10	US-PGPUB; USPAT	OR	ON	2006/02/28 13:06
S12	357	S11 and (releas\$6 mov\$6 mirror micromirror reflect\$6)	US-PGPUB; USPAT	OR	ON	2006/02/28 17:53
S13	10929	mems micromechanical\$4 microelectromechanical\$4 "micro-mechanical" "micro-electro-mechanical"	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:09
S14	1126	S13 and (silicon polysilicon "poly-si" polycrystalline si) and (remov\$6 etch\$6 sacrificial disposable)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:13

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S15	197	S13 and (silicon polysilicon "poly-si" polycrystalline si) and (remov\$6 etch\$6) and (sacrificial disposable)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 17:03
S16	372	S14 and (releas\$6 mov\$6 mirror micromirror reflect\$6)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:13
S17	499	S13 and ((silicon polysilicon "poly-si" polycrystalline si) with (remov\$6 etch\$6 sacrificial disposable))	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/02/28 13:13